Beamline	PF BL-19B			
Sample	Si wafer (substrate on carbon tape)			
Edge	Si-K			
Method	Total electron yield			
Date	2020.10.23			
Scan mode	Quick scan mode			
	Energy /eV		Step /eV	Dwell / s
	1820	1920	0.1	0.5
			Total data points	1000
			Measure time	8.3 min